

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*In re* application of: **Sang-In Lee, et al.**

Serial No. **10/524,814**

Filed: **May 5, 2006**

For: **Atomic Layer Deposition of High-K  
Metal Oxides**

Examiner: **SMITH, Bradley**

Art Unit: **2891**

Confirmation No.: **1997**

Atty. Docket No.: **067538-5170-US**

**RESPONSE/AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed May 28, 2008, please consider the following proposed amendments to the above-identified application and the remarks herein. Accompanying this Response is a Petition for Extension of Time bringing the period of response from August 28, 2008 to November 28, 2008. Please amend the application as follows.

**Amendments to the Claims** begin on page 2 of this Amendment.

**Remarks** begin on page 4 of this Amendment.